IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Somenath Mitra et al.

Application No.: 10/735,988

Filing Date: December 15, 2003

Group Art Unit: 3753

Examiner: Not Yet Assigned

For: Microfabricated Microconcentrator For Sensors And Gas Chromatography

INFORMATION DISCLOSURE STATEMENT

Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants respectfully submit this Information Disclosure Statement and a copy of the cited references pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98 in order to comply with the duty of disclosure. The enclosed Form PTO-1449 identifies the references of which Applicant is aware.

The Examiner is respectfully requested to consider the references herein and make them of record in the subject application. It is Applicant's position that the references cited pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98 are clearly not a bar to allowance of the claims in this application.

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on the date shown below.

Dated: April 15, 2004 Signature: _____ Print Name: Timothy X. Gibson

The above-captioned application has not yet received a substantive Office Action, and accordingly it is believed that no fee is necessary. However, should the Patent Office determine that a fee is due, the Commissioner is authorized to charge any such fee to Deposit Account No. 11-0223.

Dated: April 15, 2004

Respectfully submitted,

By _____

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FORM PTO-1449 (Rev. 2-32) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT *(Use several sheets if necessary)*	ATTORNEY DOCKET NO.: 436/13	APPL. NO.: 10/735,988
	APPLICANT: Somenath Mitra et al.	
	FILING DATE: December 15, 2003	GROUP ART UNIT: 3753

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	BA							

OTHER DOCUMENTS *(including Author, Title, Date, Pertinent Pages, Etc.)*

	CA	A. Friedberger et al.; A Versatile And Modularizable Micromachining Process For The Fabrication Of Thermal Microsensors And Microactuators; Journal of Micromechanics and Microengineering; 9/7/2001; pp. 623-629.
	CB	Ivonne Schneegaβ, et al.; Miniaturized Flow-Through PCR With Different Template Types In A Silicon Chip Thermocycler; Institute of Physical High Technology; 8/9/2001; pp. 1-16.
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	CD	*Yukikio Hosoda et al.; Fabrication And Applications Of Polymer-Based Microchannel-Heater Chip As Microreactor; Micro Total Analysis Systems, 2002.
	CE	*J. Laconte et al.; SOI CMOS Compatible Low-Power Microheater Optimization And Fabrication For Smart Gas Sensor Implementations; IEEE International Conference on Sensors; 2002.
	CF	*Gwiy-Sang Chung et al.; The Fabrication Of Micro-Heaters With Low-Power Consumption Using SOI And Trench Structures; Metals and Materials International; 2002.
	CG	*V. Guarnieri et al.; Low-Power Silicon Microheaters On A Thin Dielectric Membrane With Thick-Film Sensing Layer For Gas Sensor Applications; Microelectronics, Microsystems and Nanotechnology; 2000.
	CH	*Yaowu Mo et al.; Low-Voltage And Low-Power Optimization Of Micro-Heater And Its On-Chip Drive Circuitry For Gas Sensor Array; Sensors and Actuators, A: Physical, 2002.

***ABSTRACT ONLY**

EXAMINER	DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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	CI	*W. C. Tian et al.; Freestanding Microheaters In Si With High Aspect Ratio Microstructures; Journal of Vacuum Science & Technology, B: Microelectronics and Nanometer Structures; 2002.
	CJ	*Tailian Chen et al.; Coalescence Of Bubbles In Nucleate Boiling On Microheaters; International Journal of Heat and Mass Transfer; 2002.
	CK	*A. V. Korlyakov et al.; Infrared Microradiator Based On SiC-on Insulator Thin-Film Structures; Journal of Optical Technology; 2001.
	CL	*Y. Mo. et al.; Micro-Machined Gas Sensor Array Based On Metal Film Micro-Heater; Sensors and Actuators, B: Chemical; 2001.
	CM	*Gwiy-Sang Chung et al.; Fabrication Of Pt Microheater Using Aluminum Oxide As A Medium Layer And Its Characteristics; Sensors and Materials; 1998.
	CN	*Carole Rossi et al.; Realization And Performance Of Thin SiO2/SiNx Membrane For Microheater Applications; Sensors and Actuators, A: Physical; 1998.

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